

Supplementary Materials

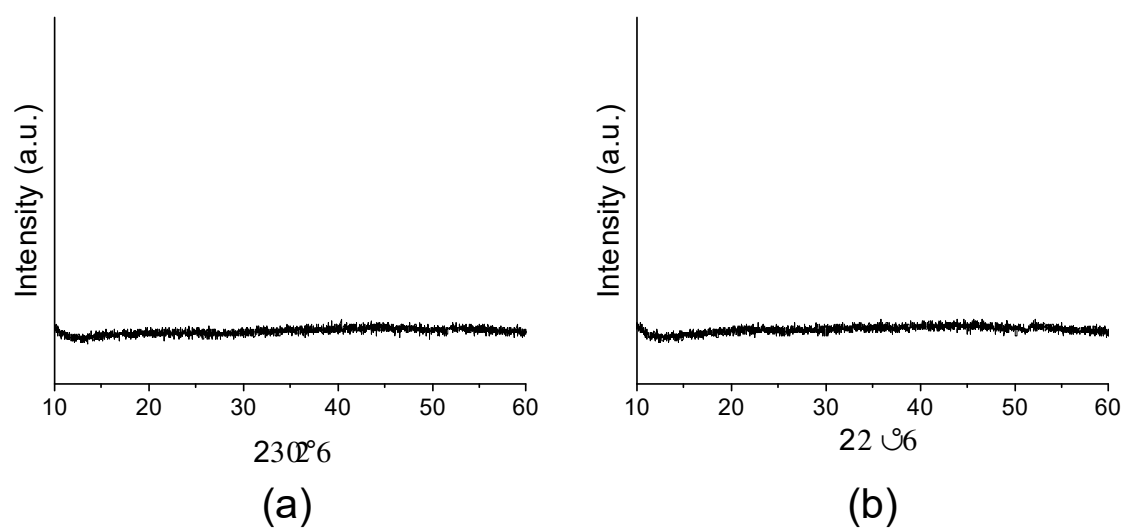


Figure S1. XRD patterns of SiC_xN_y films sputtered at (a) 25 and (b) 300 °C.

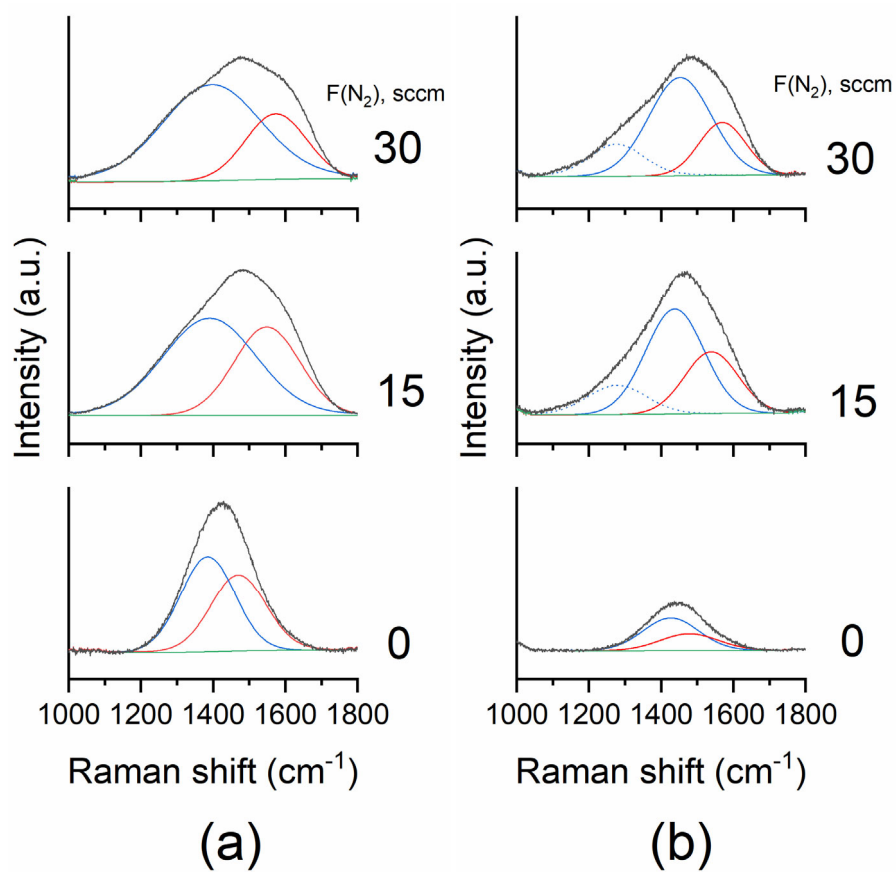


Figure S2. Deconvolution of Raman spectra of SiC_xN_y films sputtered at (a) 25 and (b) 300 °C.